ABSTRACT OF THE DISCLOSURE

The invention relates to a bistable MEMS microswitch produced on a substrate and capable of electrically connecting the ends (12, 13) of at least two conductive tracks (2, 3), including a beam (6) suspended above the surface of the substrate, wherein the beam is embedded at its two ends and is subjected to compressive stress when it is in the non-deformed position. The beam (6) has an electrical contact (7) arranged so as to produce a lateral connection with the ends of the two conductive tracks when the beam is deformed in a horizontal direction with respect to the surface of the substrate. Actuators (40, 50) enable the beam to be placed in a first deformed position, corresponding to a first stable state, or in a second deformed position, corresponding to a second stable state, and the electrical contact ensures the connection of the ends of the two conductive tracks.

Figure 2